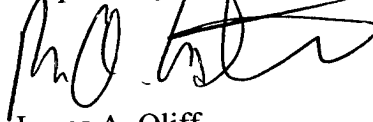


REMARKS

Claims 1-6 are pending. By this Preliminary Amendment, the specification is amended. Prompt and favorable examination on the merits is respectfully solicited.

The attached Appendix includes marked-up copies of each rewritten paragraph (37 C.F.R. 1.121(b)(iii)).

Respectfully submitted,



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JAO:MAC/cmm

Attachment:
Appendix

Date: March 28, 2001

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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
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APPENDIX

Changes to Specification:

The following are marked-up versions of the amended paragraphs:

Page 21, lines 7-21

Fig. 3A is a schematic diagram to show directions of the fast axis at birefringence measuring points ~~P₃₁~~ *P₃₁, P₃₂, P₃₃, P₃₄ and P₃₅* ~~P₃₂, P₃₃, and P₃₄~~ located at respective distances r_1 , r_2 , r_3 , r_4 , and r_5 from the center O on the effective section of another optical member L₃, similar to Fig 1A. In this case, the directions of the fast axis, W₃₁, W₃₂, W₃₃, W₃₄, and W₃₅, at the measuring points P₁₁ to P₁₄ are such that those at the measuring points P₃₁ to P₃₃ are parallel to the direction of the straight line Q₃, i.e., to the radial direction, but those at the measuring points P₃₃, P₃₄ are perpendicular to the radial direction. Therefore, the distribution in the radial direction of the signed birefringence values A₃₁ to A₃₅ at the measuring points P₃₁ to P₃₅ is depicted, for example, as a profile of Fig. 3B.

Page 54, lines 23-26 and Page 55, lines 1-14

The wafer W is mounted on a leveling stage (not illustrated) and this leveling stage is set on a Z-stage 301 which can be finely moved in the optical-axis direction (Z-direction) of the projection optical

system by a driving motor ³³⁰~~320~~. The Z-stage 301 is mounted on an XY stage 315 which can be moved in the two-dimensional directions (XY directions) in the step-and-repeat method by the driving motor 320. The reticle R is mounted on a reticle stage 306 which is two-dimensionally movable in the horizontal plane. The exposure light from the exposure light source 303 uniformly illuminates the pattern formed in the reticle R through the illumination optical system 302 and the pattern image of the reticle R is printed into a shot area of the wafer W by the projection optical system 304. This exposure light can be one of the wavelength selected from 248 nm (KrF excimer laser), 193 nm (ArF excimer laser), 157 nm (F₂ laser), and so on.

1. The first group of people who are not allowed to enter the country are those who are on the "no-fly" list. This list is maintained by the Department of Homeland Security and includes individuals who are suspected of being involved in terrorism or other activities that could threaten the security of the United States.

A-3

Page 63, lines 9-26 and Page 64 lines 1-3.

The projection optical system 304 illustrated in Fig. ~~44~~⁹ is constructed by combining the optical elements so as to satisfy the placement condition that the signed birefringence characteristic value of the entire projection optical system is not less than -0.5 nor more than +0.5 nm/cm. The optical members are also combined with each other so as to further satisfy the placement condition that the Strehl value of signed birefringence value based on the effective path of the entire projection optical system is not less than 0.93. Further, the optical members used are those satisfying the following conditions; the signed birefringence values around the center of the effective section are -0.2 to +0.2 nm/cm; the radial distribution of the mean signed birefringence values has no extremum except at the center; the difference ΔB_i between maximum and minimum of the mean signed birefringence values is not more than 2.0 nm/cm; the maximum F_i of slope of the distribution curve in the radial direction of the mean signed birefringence values B_{ij} is not more than 0.2 nm/cm per 10 mm of radial width.